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IN THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application:

1. (Currently Amended) A manufacturing method of a display device in a plasma treatment chamber comprising the step of:

partially forming a conductor film over a substrate;

forming a resist mask by use of liquid droplet jetting means, over the conductor film;

forming a wiring by partially etching [[a]] the conductor film over [[a]] the substrate by discharging a plasma to the plasma treatment chamber from a plasma treatment means having one set of electrodes contained therein for generating the plasma at a pressure of 5 to 800 Torr from a first reactive gas introduced to the plasma treatment means;

after switching the first reactive gas to a second reactive gas, ashing the resist mask by partially blowing the second reactive gas in the plasma treatment chamber at the pressure of 5 to 800 Torr;

providing the plasma treatment means in the plasma treatment chamber;

providing one electrode of the set of electrodes which surrounds an [[the]] other electrode of the set of electrodes; and

providing a distal portion of the one electrode of the set of electrodes being pointed toward the other electrode of the set of electrodes [[line]],

wherein the distal portion of the one electrode of the set of electrodes has a sharp angle shape.

2. (Currently Amended) A manufacturing method of a display device in a plasma treatment chamber comprising the step of:

partially forming a conductor film over a substrate;

forming a resist mask by use of liquid droplet jetting means, over the conductor film;

forming a wiring by partially etching [[a]] the conductor film over [[a]] the substrate by discharging a plasma to the plasma treatment chamber from a plasma treatment means having a plurality of sets of electrodes contained therein for generating the plasma at a pressure of 5 to 800 Torr from a first reactive gas introduced to the plasma treatment means;

after switching the first reactive gas to a second reactive gas, ashing the resist mask by

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providing the plasma treatment means in the plasma treatment chamber;
providing one electrode of the plurality of sets of electrodes which surrounds an ~~[[the]]~~ other electrode of the plurality of sets of electrodes, respectively; and
providing a distal portion of the one electrode of the plurality of sets of electrodes being pointed toward the other electrode of the plurality of sets of electrodes ~~[[line]]~~, respectively,
wherein the distal portion of the one electrode of the plurality of sets of electrodes has a sharp angle shape.

3. (Canceled)

4. (Currently Amended) A manufacturing method of a display device comprising the steps of:

forming a conductor film over a substrate;

forming a resist mask over the conductor film;

partially etching the conductor film at a pressure of 5 to 800 Torr by discharging a plasma to a plasma treatment chamber from a plasma treatment means having one set of electrodes contained therein for generating the plasma from a first reactive gas introduced to the plasma treatment means, over the resist mask thereby forming a wiring;

after switching the first reactive gas to a second reactive gas, ashing the resist mask by partially blowing the second reactive gas in the plasma treatment chamber at the pressure of 5 to 800 Torr;

providing the plasma treatment means in the plasma treatment chamber;

providing one electrode of the set of electrodes which surrounds an ~~[[the]]~~ other electrode of the set of electrodes; and

providing a distal portion of the one electrode of the set of electrodes being pointed toward the other electrode of the set of electrodes ~~[[line]]~~.

wherein the distal portion of the one electrode of the set of electrodes has a sharp angle shape.

5. (Currently Amended) A manufacturing method of a display device comprising the steps of:

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partially etching the conductor film at a pressure of 5 to 800 Torr by discharging a plasma to a plasma treatment chamber from a plasma treatment means having a plurality of sets of electrodes contained therein for generating the plasma from a first reactive gas introduced to the plasma treatment means, over the resist mask thereby forming a wiring;

after switching the first reactive gas to a second reactive gas, ashing the resist mask by partially blowing the second reactive gas in the plasma treatment chamber at the pressure of 5 to 800 Torr;

providing the plasma treatment means in the plasma treatment chamber;

providing one electrode of the plurality of sets of electrodes which surrounds an [[the]] other electrode of the plurality of sets of electrodes, respectively; and

providing a distal portion of the one electrode of the plurality of sets of electrodes being pointed toward the other electrode of the plurality of sets of electrodes [[line]], respectively,

wherein the distal portion of the one electrode of the plurality of sets of electrodes has a sharp angle shape.

6. (Previously Presented) The manufacturing method of the display device according to any of claims 1, 2, 4 and 5, wherein the substrate has a size of 1,000 x 1,200 mm² or more.

7. (Previously Presented) The manufacturing method of the display device according to any of claims 1, 2, 4 and 5, wherein the plasma treatment means scans the substrate in one direction.

8. (Previously Presented) The manufacturing method of the display device according to any of claims 1, 2, 4 and 5, wherein the plasma treatment means alternately scans the substrate in a row direction and in a column direction.

9. (Previously Presented) The manufacturing method of the display device according to any of claims 4 and 5, wherein the resist mask is formed by use of liquid droplet jetting means.

10-11. (Canceled)

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12. (Previously Presented) The manufacturing method of the display device according to any of claims 1, 2, 4 and 5, further comprising:

moving the plasma treatment means along a rail.